



Research article

Rolling-horizon supply chain capacity planning for IC design house considering forecast evolution and capacity regret

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Appendix

Appendix: Model notation description

Sets & Indices

r	Index value of review epoch
t	Index value of planning period
W	Set of wafer types ($w = 1, 2, 3, \dots, W $)
P	Set of product types ($p = 1, 2, 3, \dots, P $)
B	Set of banks. Includes a wafer bank B_W and a FG bank B_P
L	Set of sites. Includes wafer fab sites L_F , wafer probe sites L_O , assembly sites L_A , and final test sites L_T
M	Set of machines ($m = 1, 2, 3, \dots, M $)
S	Set of demand scenarios ($s = 1, 2, 3, \dots, S $)

Parameters

R	The total number of review epoch
T	The total length of planning periods at each epoch r
Δ	The length of planning periods for the back-end process based on receiving actual orders at each epoch r
δ	The length of planning periods for the wafer fab process based on demand forecasts at each epoch r
df_{pt}^s	Demand forecast quantity of product p required in period t under scenario s
cc_{lw}	Consumed capacity of site l to produce a unit of wafer w , $l \in L_F, L_O$
cc_{lwp}	Consumed capacity of site l to produce a unit of product p with wafer w , $l \in L_A$
cc_{lmp}	Consumed capacity of machine m in site l to produce a unit of product p , $l \in L_T$
yr_{lwp}	Yield rate of site l to process wafer w for product p , $l \in L_F, L_O$
yr_{lp}	Yield rate of site l for product p , $l \in L_A, L_T$
gd_{wp}	Gross die of wafer w for product p
lt_l	Lead time in non-bottlenecks site l , $l \in L_F, L_O, L_A, L_T$
$tt_{ll'}$	Transportation time from site l to site l' , $l \in L_F, B_W, L_O, L_A, L_T, l' \in B_W, L_O, L_A, L_T, B_P$
fc_{lp}	Fixed cost when product p is processed in site l , $l \in L_F, L_O, L_A, L_T$
oc_l	Capacity oversupply cost of site l , $l \in L_F, L_O, L_A$
oc_{lm}	Capacity oversupply cost of site l with machine m , $l \in L_T$
oc_p	Capacity oversupply cost of product p
sc_l	Capacity shortage cost of site l , $l \in L_F, L_O, L_A$
sc_{lm}	Capacity shortage cost of site l with machine m , $l \in L_T$
sc_p	Capacity shortage cost of product p
pc_{lwp}	Production cost of site l to process wafer w for product p , $l \in L_F, L_O$
pc_{lp}	Production cost of site l to process product p , $l \in L_A$
pc_{lmp}	Production cost of site l with machine m to process product p , $l \in L_T$
$tc_{ll'}$	Transportation cost per unit from site l to location l' , $l \in L_F, B_W, L_O, L_A, L_T, l' \in B_W, L_O, L_A, L_T, B_P$
a_{wp}	Binary parameter: 1, if product p can be produced with wafer w ; 0, otherwise
t_{lmp}	Binary parameter: 1, if product p can be tested with machine m in site l ; 0, otherwise, $l \in L_T$
UBP	Upper bound for production quantity
UBT	Upper bound for transportation quantity
UBC_l	Upper bound for maximum reservable capacity of site l , $l \in L_F, L_O, L_A$
UBC_{lm}	Upper bound for maximum reservable capacity of machine m of site l , $l \in L_T$

Decision Variables

Q_{lwpt}^{s1}	Quantity of wafer w for product p start to be processed in site l in period t under scenarios s , $l \in L_F, L_O, L_A$
Q_{lmp}^{s1}	Quantity of product p start to be processed by machine m in site l in period t under scenarios s , $l \in L_T$

Q_{lwpt}^{s2}	Quantity of wafer w for product p completed in site l in period t under scenarios s , $l \in L_F, L_O$
Q_{lpt}^{s2}	Quantity of product p completed in site l in period t under scenarios s , $l \in L_A$
Q_{lmpt}^{s2}	Quantity of product p completed by machine m in site l in period t under scenarios s , $l \in L_T$
$T_{ll'wpt}^{s1}$	Quantity of wafer w for product p shipped from site l to site l' in period t under scenarios s , $l \in L_F, B_W, L_O$, $l' \in B_W, L_O, L_A$
$T_{ll'pt}^{s1}$	Quantity of product p shipped from site l to site l' in period t under scenarios s , $l \in L_A, L_T$, $l' \in L_T, B_P$
$T_{ll'wpt}^{s2}$	Quantity of wafer w for product p received by site l' come from site l in period t under scenarios s , $l \in L_F, B_W, L_O$, $l' \in B_W, L_O, L_A$
$T_{ll'pt}^{s2}$	Quantity of product p received by site l' come from site l in period t under scenarios s , $l \in L_A, L_T$, $l' \in L_T, B_P$
CE_{lt}	Existing available capacity of site l in period t , $l \in L_F, L_O, L_A$
CE_{lmt}	Existing available capacity of machine m of site l in period t , $l \in L_T$
OR_{lt}^s	Regret of capacity oversupply of site l in period t under scenarios s , $l \in L_F, L_O, L_A$
OR_{lmt}^s	Regret of capacity oversupply of machine m of site l in period t under scenarios s , $l \in L_T$
OR_{pt}^s	Regret of demand oversupply of product p in period t under scenarios s
SR_{lt}^s	Regret of capacity shortage of site l in period t under scenarios s , $l \in L_F, L_O, L_A$
SR_{lmt}^s	Regret of capacity shortage of machine m of site l in period t under scenarios s , $l \in L_T$
SR_{pt}^s	Regret of demand shortage of product p in period t under scenarios s
X_{lpt}^s	Binary variable: 1, if product p is processed in site l in period t under scenarios s ; 0, otherwise, $l \in L_F, L_O, L_A, L_T$
Y_{lt}^s	Binary variable: 1, if capacity is shortage of site l in period t under scenario s ; 0, otherwise, $l \in L_F, L_O, L_A$
Y_{lmt}^s	Binary variable: 1, if capacity is shortage of machine m of site l in period t under scenario s , $l \in L_T$
Y_{pt}^s	Binary variable: 1, if demand is shortage of product p in period t under scenario s ; 0, otherwise

